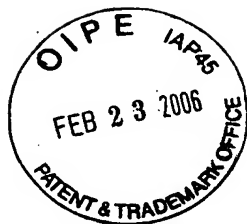


IFW



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Ikuhito ONODERA

Group Art Unit: 2653

Application No.: 10/076,653

Examiner: C. MAGEE

Filed: February 19, 2002

Docket No.: 111984

For: METHOD FOR FABRICATING A THIN FILM MAGNETIC HEAD AND WAFER
STRUCTURE

REQUEST FOR RECONSIDERATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the November 23, 2005 Office Action, reconsideration of the rejection is respectfully requested in light of the following remarks.

Claims 1-18 are currently pending.

The Office Action rejects claims 1-18 under 35 U.S.C. §103(a) over U.S. Patent No. 6,195,871 to Watanuki in view of U.S. Patent No. 6,747,846 to Kato et al. (Kato). This rejection is respectfully traversed.

Kato was filed on February 15, 2002. This is after March 2, 2001, which is the filing date of the Japanese priority application of this application. Further, JP 2001-262653, the document forming the basis for Kato was not published until March 14, 2003. To perfect Applicant's claim for priority, Applicant respectfully submits an accurate English translation of the Japanese priority application. Accordingly, Kato is no longer prior art to this application.